

A Method For Forming A Piezoelectric Device

Abstract

5 There is provided a method for forming a piezoelectric device comprising the steps of: (a) depositing a first electrode layer; (b) depositing a piezoelectric material layer on the first electrode layer to thereby cover the first electrode layer while leaving a region of the first
10 electrode layer uncovered; (c) depositing a second electrode layer on the piezoelectric material layer; (d) depositing a piezoelectric material layer on the second electrode layer to thereby cover the second electrode layer while leaving a region of the second electrode
15 layer uncovered; and (e) repeating steps (a) to (c), and optionally step (d), to build multiple repeating first electrode layers separated from the second electrode layers by piezoelectric material layers, wherein all of the uncovered regions of the first electrode layers
20 converge at a point A to integrally form a first electrode and all of the uncovered regions of the second electrode layers converge at a point B to integrally form a second electrode in which point A is displaced at a distance from point B.

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(Fig. 1(s) and Fig. 1(t))